

*a1
cancel*
[Claim 2 has been amended as follows:]

2. (Amended) A method as claimed in claim 1 comprising controlling said vapor deposition to reduce said density of the fluorescent layer by between 5% to 50% of said density that said fluorescent material has as a solid.

a2
[Claim 5 has been amended as follows:]

5. (Amended) A method as claimed in claim 3 wherein said vapor jet is produced in a vapor-deposition apparatus, and comprising introducing inert gas into said vapor deposition apparatus at a gas pressure below 10 Pa.

a3
[Claim 7 has been amended as follows:]

7. (Amended) A method as claimed in claim 4 comprising diverting said inert gas relative to said vapor jet with a baffle before introducing said inert gas into said vapor jet, causing said inert gas to be introduced indirectly into said vapor jet.
